L Number	Hits	Search Text	DB	Time stamp
-	35666	mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)	USPAT; US-PGPUB	2004/09/01 11:54
-	235	(mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (fill adj2 factor$1)	USPAT; US-PGPUB	2004/09/01 11:54
-	204	((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (fill adj2 factor$1)) and (mirror$1 reflect$3)	USPAT; US-PGPUB	2004/09/01 11:55
-	150	(((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (fill adj2 factor$1)) and (mirror$1 reflect$3)) and wavelength$1	USPAT; US-PGPUB	2004/09/01 11:55
-	81	((((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (fill adj2 factor$1)) and (mirror$1 reflect$3)) and wavelength$1) and ((pivot$3 tilt$3 rotat$3 actuat$3) with (mirror$1 micromirror$1 (micro near2 mirror$1)))	USPAT; US-PGPUB	2004/09/01 11:57
-	37	(((((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (fill adj2 factor$1)) and (mirror$1 reflect$3)) and wavelength$1) and ((pivot$3 tilt$3 rotat$3 actuat$3) with (mirror$1 micromirror$1 (micro near2 mirror$1)))) and multiplex$3	USPAT; US-PGPUB	2004/09/01 12:07
-	73	(mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (high adj2 fill adj2 factor)	USPAT; US-PGPUB	2004/09/01 12:10
-	22	((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (high adj2 fill adj2 factor)) and multiplex$3	USPAT; US-PGPUB	2004/09/01 12:08
-	20	(((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (high adj2 fill adj2 factor)) and multiplex$3) and mirror$1	USPAT; US-PGPUB	2004/09/01 12:09
-	41	(mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and ((high adj2 fill adj2 factor) same (mirror$1 reflect$3))	USPAT; US-PGPUB	2004/09/01 12:10

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-	9	((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and ((high adj2 fill adj2 factor) same (mirror$1 reflect$3))) and multiplex$3	USPAT; US-PGPUB	2004/09/01 12:19
-	44631	mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 18:34
-	232	(mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (fill adj2 factor)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 12:19
-	200	((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (fill adj2 factor)) and (reflect$3 mirror$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 12:20
-	35188	(((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (fill adj2 factor)) and (reflect$3 mirror$1)) ((monolith$3 (single near2 crystal)) near4 substrate$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 12:21
-	14	(((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (fill adj2 factor)) and (reflect$3 mirror$1)) and ((monolith$3 (single near2 crystal)) near4 substrate$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 12:21
-	10	((((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (fill adj2 factor)) and (reflect$3 mirror$1)) and ((monolith$3 (single near2 crystal)) near4 substrate$1)) and (multiplex$3 wavelengths)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 12:46
-	2	6137941.pn.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 14:05
-	9290	mirror$1 near4 array	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 14:05
-	3043	(mirror$1 near4 array) and (multiplex$3 wavelengths)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 14:06
-	79	((mirror$1 near4 array) and (multiplex$3 wavelengths)) and (fill adj2 factor)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 14:06

-	4162	(mirror$1 near4 array) and (multiplex$3 wavelength$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 14:06
-	109	((mirror$1 near4 array) and (multiplex$3 wavelength$1)) and (fill adj2 factor)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 14:35
-	92	(((mirror$1 near4 array) and (multiplex$3 wavelength$1)) and (fill adj2 factor)) and (tilt$3 pivot$3 rotat$3 actuat$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 19:00
-	7	(US-6263123-$ or US-6760144-$ or US-6778728-$).did. or (US-20040130774-$ or US-20040165243-$ or US-20030223679-$ or US-20010026674-$).did.	USPAT; US-PGPUB	2004/09/01 15:26
-	8	(US-5965886-$ or US-6778728-$ or US-6760144-$ or US-6263123-$).did. or (US-20040130774-$ or US-20040165243-$ or US-20030223679-$ or US-20010026674-$).did.	USPAT; US-PGPUB	2004/09/01 15:27
-	7	(US-6778728-$ or US-5965886-$ or US-6263123-$ or US-6760144-$).did. or (US-20030223679-$ or US-20040165243-$ or US-20040130774-$).did.	USPAT; US-PGPUB	2004/09/01 15:29
-	6	((US-6778728-$ or US-5965886-$ or US-6263123-$ or US-6760144-$).did. or (US-20030223679-$ or US-20040165243-$ or US-20040130774-$).did.) and (((((mirror$1 near4 array) and (multiplex$3 wavelength$1)) and (fill adj2 factor)) and (tilt$3 pivot$3 rotat$3 actuat$3))	USPAT; US-PGPUB	2004/09/01 15:33
-	7	((US-6778728-$ or US-5965886-$ or US-6263123-$ or US-6760144-$).did. or (US-20030223679-$ or US-20040165243-$ or US-20040130774-$).did.) and (multiplex$3 wavelength$1)	USPAT; US-PGPUB	2004/09/01 16:10
-	7	(((US-6778728-$ or US-5965886-$ or US-6263123-$ or US-6760144-$).did. or (US-20030223679-$ or US-20040165243-$ or US-20040130774-$).did.) and (multiplex$3 wavelength$1)) and (tilt$3 pivot$3 rotat$3 actuat$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 16:10
-	7	((((US-6778728-$ or US-5965886-$ or US-6263123-$ or US-6760144-$).did. or (US-20030223679-$ or US-20040165243-$ or US-20040130774-$).did.) and (multiplex$3 wavelength$1)) and (tilt$3 pivot$3 rotat$3 actuat$3)) and (fill adj2 factor)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 16:10
-	2	6657770.pn.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 16:09
-	1	6657770.pn. and (multiplex$3 wavelength$1)	USPAT; US-PGPUB	2004/09/01 16:10
-	1	(6657770.pn. and (multiplex$3 wavelength$1)) and (tilt$3 pivot$3 rotat$3 actuat$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 16:10
-	0	((6657770.pn. and (multiplex$3 wavelength$1)) and (tilt$3 pivot$3 rotat$3 actuat$3)) and (fill adj2 factor)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 16:10
-	4	(US-6263123-$ or US-6760144-$ or US-6778728-$).did. or (US-20030223679-$).did.	USPAT; US-PGPUB	2004/09/01 17:55
-	3	((US-6263123-$ or US-6760144-$ or US-6778728-$).did. or (US-20030223679-$).did.) and (attenuat$4 block$3)	USPAT; US-PGPUB	2004/09/01 18:24

-	3	((US-6263123-$ or US-6760144-$ or US-6778728-$).did. or (US-20030223679-$).did.) and (attenuat$4 block$3)	USPAT; US-PGPUB	2004/09/01 18:24
-	77	(mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (high adj2 fill adj2 factor)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 18:42
-	232	(mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (fill adj2 factor)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/03 10:33
-	133	((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (fill adj2 factor)) and (attenuat$3 block$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 18:35
-	113	(((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (fill adj2 factor)) and (attenuat$3 block$3)) and (tilt$3 pivot$3 rotat$3 actuat$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 18:35
-	38	(((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (fill adj2 factor)) and (attenuat$3 block$3)) and ((tilt$3 pivot$3 rotat$3 actuat$3) same ((mirror$1 micromirror$1 (micro adj mirror$1)) with array))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 18:37
-	82	(((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (fill adj2 factor)) and (attenuat$3 block$3)) and ((tilt$3 pivot$3 rotat$3 actuat$3) same ((mirror$1 micromirror$1 (micro adj mirror$1)) reflect$4))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 18:58
-	48	((((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (fill adj2 factor)) and (attenuat$3 block$3)) and ((tilt$3 pivot$3 rotat$3 actuat$3) same ((mirror$1 micromirror$1 (micro adj mirror$1)) reflect$4))) and (multiplex$3 wavelengths (wavelength near3 channels))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 18:55
-	14	(((((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (fill adj2 factor)) and (attenuat$3 block$3)) and ((tilt$3 pivot$3 rotat$3 actuat$3) same ((mirror$1 micromirror$1 (micro adj mirror$1)) reflect$4))) and (multiplex$3 wavelengths (wavelength near3 channels))) and (high adj2 fill adj2 factor)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 18:42

-	1	(((((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (fill adj2 factor)) and (attenuat$3 block$3)) and ((tilt$3 pivot$3 rotat$3 actuat$3) same ((mirror$1 micromirror$1 (micro adj mirror$1)) reflect$4))) and (multiplex$3 wavelengths (wavelength near3 channels))) and cantilever	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 18:58
-	2327	(mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and cantilever	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 18:58
-	1230	((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and cantilever) and ((mirror$1 micromirror$1 (micro adj mirror$1) reflect$4))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 18:59
-	134	(((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and cantilever) and ((mirror$1 micromirror$1 (micro adj mirror$1) reflect$4))) and ((attenuat$3 block) same (wavelength$1 channel$1 multiplex$3))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 19:37
-	124	((((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and cantilever) and ((mirror$1 micromirror$1 (micro adj mirror$1) reflect$4))) and ((attenuat$3 block) same (wavelength$1 channel$1 multiplex$3))) and (tilt$3 pivot$3 rotat$3 actuat$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 19:00
-	4226	(mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and ((attenuat$3 block) same (wavelength$1 channel$1 multiplex$3))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 19:37
-	91	((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and ((attenuat$3 block) same (wavelength$1 channel$1 multiplex$3))) and (assymetric offset) near5 (pivot$3 tilt$3 rotat$3 actuat$3 axis axes)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 19:38
-	91	((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and ((attenuat$3 block) same (wavelength$1 channel$1 multiplex$3))) and ((assymetric$2 offset) near5 (pivot$3 tilt$3 rotat$3 actuat$3 axis axes))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/01 19:38
-	233	(mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (fill adj2 factor)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/03 10:33

-	135	((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (fill adj2 factor)) and (multiplex$4 wavelengths channels)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/03 10:34
-	66	(((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (fill adj2 factor)) and (multiplex$4 wavelengths channels)) and (attenat$3 block$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/03 10:35
-	1	((((mems or mem or microelectromechanical or micromechanical or (micro near2 electro near2 mechanical) or (micro near2 mechanical) or microelectrical or microelectricalmechanical or (micro near2 electrical) or (micro near2 electrical near2 mechanical)) and (fill adj2 factor)) and (multiplex$4 wavelengths channels)) and (attenat$3 block$3)) and (electrode with potential with mirror)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/03 10:42
-	0	(mirror with (landing) with electrode with potential) and attenuat$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/03 10:43
-	20	mirror with (landing) with electrode with potential	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/03 10:47
-	4	(mirror with (landing) with electrode with potential) and multiplex$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/03 10:45
-	41	mirror with electrode with ("same" near3 potential)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/03 10:47
-	5	(mirror with electrode with ("same" near3 potential)) and attenuat$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/03 10:48
-	5	((mirror with electrode with ("same" near3 potential)) and attenuat$3) not ((mirror with (landing) with electrode with potential) and multiplex$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/03 10:56
-	34969	mem or mems	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/03 10:56
-	1746	(mem or mems) and (circuit near5 substrate)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/03 10:57
-	24	(mem or mems) and (fabricate near3 circuit near5 substrate)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/03 10:58

-	0	((mem or mems) and (fabricate near3 circuit near5 substrate)) and attenuat$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/03 10:58
-	3	((mem or mems) and (fabricate near3 circuit near5 substrate)) and multiplex	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/03 11:08
-	27364	wavelength near3 multiplex$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/03 11:08
-	963	(wavelength near3 multiplex$3) and ((mirror micromirror (micro near2 mirror$1)) with (tilt$3 rotat$3 pivot$3))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/03 11:10
-	0	((wavelength near3 multiplex$3) and ((mirror micromirror (micro near2 mirror$1)) with (tilt$3 rotat$3 pivot$3))) and ((rotat$3 tilt$3 pivot$3) with (center near4 gravity))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/03 11:10
-	15	(wavelength near3 multiplex$3) and ((off near3 center) with (tilt$3 rotat$3 pivot$3))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/03 11:10
-	1	(US-20020135864-$).did.	US-PGPUB	2004/09/03 11:14
-	8	(US-6760144-$ or US-6778728-$ or US-5965886-$ or US-6263123-$).did. or (US-20030112507-$ or US-20030223679-$ or US-20040125361-$ or US-20020135864-$).did.	USPAT; US-PGPUB	2004/09/03 14:09
-	1	((US-6760144-$ or US-6778728-$ or US-5965886-$ or US-6263123-$).did. or (US-20030112507-$ or US-20030223679-$ or US-20040125361-$ or US-20020135864-$).did.) and (polish$3 near4 mirror)	USPAT; US-PGPUB	2004/09/03 11:16
-	1	((US-6760144-$ or US-6778728-$ or US-5965886-$ or US-6263123-$).did. or (US-20030112507-$ or US-20030223679-$ or US-20040125361-$ or US-20020135864-$).did.) and (polish$3 near4 mirror)	USPAT; US-PGPUB	2004/09/03 11:16
-	4693	((359/214,224,291,290,295,298) (385/15,18) (310/309)).ccls.	USPAT; US-PGPUB	2004/09/03 14:10
-	1155	(((359/214,224,291,290,295,298) (385/15,18) (310/309)).ccls.) and mem$1	USPAT; US-PGPUB	2004/09/03 14:10
-	1	((((359/214,224,291,290,295,298) (385/15,18) (310/309)).ccls.) and mem$1) and wavlength$1	USPAT; US-PGPUB	2004/09/03 14:10
-	710	((((359/214,224,291,290,295,298) (385/15,18) (310/309)).ccls.) and mem$1) and wavelength$1	USPAT; US-PGPUB	2004/09/03 14:10
-	386	(((((359/214,224,291,290,295,298) (385/15,18) (310/309)).ccls.) and mem$1) and wavelength$1) and ((mirror$1 micromirror$1) with (tilt$3 rotat$3 pivot$3))	USPAT; US-PGPUB	2004/09/03 14:11

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